



IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Boyd et al

Serial No. 10/606,022

Filed: June 24, 2003

For: SYSTEM AND METHOD
FOR INTEGRATING IN-SITU
METROLOGY WITHIN A
WAFER PROCESS

Examiner: Unassigned

Art Unit: 1746

Atty Docket No. LAM2P425

DATE: May 25, 2004

CERTIFICATE OF MAILING

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Alexandria, VA 22313-1450 on **May 25, 2004**.

Signed: _____



Sylvia Castillo

PRELIMINARY AMENDMENT

Commissioner for Patents
Alexandria, VA 22313-1450

Please amend the above-referenced application as follows:

Amendments to the Specification begin on page 2 of this paper.

Remarks begin on page 3 of this paper.